IN THE CLAIMS:

Please cancel claims 1, 5, 7, 8, and 12-18 without prejudice and amend the claims as follows:

1. (Canceled)

2. (Currently Amended) ~~The~~ An apparatus ~~of claim 1, further~~ for delivering processing gas from a vaporizer to a processing system, comprising:

a valve connected between the vaporizer and the processing system, the valve having a valve input connected to a vaporizer output and a first valve output connected to a processing system input and a second valve output connected to a bypass line;

a controller for switching the valve between the first valve output and the second valve output; and

a second valve connected between a carrier gas source, a divert gas source and the vaporizer, the second valve having a first valve input connected to the carrier gas source, a second valve input connected to the divert gas source, and a valve output connected to a vaporizer input.

3. (Original) The apparatus of claim 2, wherein the controller is connected to switch the second valve between the first valve input and the second valve input.

4. (Previously Presented) The apparatus of claim 3, wherein the controller is connected to correspondingly switch the valve and the second valve.

5. (Canceled)

6. (Currently Amended) ~~The~~ An apparatus ~~of claim 5, further~~ for processing a substrate, comprising:

a chamber having a gas input;

a vaporizer;

a valve connected between the vaporizer and the chamber, the valve having a valve input connected to a vaporizer output and a first valve output connected to the gas input and a second valve output connected to a bypass line;

a controller for switching the valve between the first valve output and the second valve output; and

a second valve connected between a carrier gas source, a divert gas source and the vaporizer, the second valve having a first valve input connected to the carrier gas source, a second valve input connected to the divert gas source, and a valve output connected to a vaporizer input.

7-8. (Canceled)

9. (Currently Amended) ~~The~~ An apparatus ~~of claim 5, further~~ for processing a substrate, comprising:

a chamber having a gas input;

a vaporizer;

a valve connected between the vaporizer and the chamber, the valve having a valve input connected to a vaporizer output and a first valve output connected to the gas input and a second valve output connected to a bypass line;

a controller for switching the valve between the first valve output and the second valve output; and

at least one input valve connected between a gas source and the valve, the input valve having a plurality of inputs selectably connected to a plurality of gas supplies of the gas source and an output connected to the valve input.

10. (Previously Presented) The apparatus of claim 9, wherein the controller is connected to switch the input valve between a first valve input of the plurality of inputs and a second valve input of the plurality of inputs.

11. (Previously Presented) The apparatus of claim 10, wherein the controller is connected to correspondingly switch the valve and the input valve.

12-18. (Canceled)

19. (Currently Amended) ~~The~~ An apparatus ~~of claim 18, further~~ for delivering processing gas from a vaporizer to a processing system, comprising:

a valve means for selectively delivering gas to a processing system input and to a bypass line, the valve means being connected between the vaporizer and the processing system, wherein the valve means comprises a valve having a valve input connected to a vaporizer output and a first valve output connected to the processing system input and a second valve output connected to the bypass line;

a controller means for switching the valve means between the processing system input and to the bypass line; and

a second valve means connected between a carrier gas source, a divert gas source and the vaporizer, the second valve means having a first valve input connected to the carrier gas source, a second valve input connected to the divert gas source, and a valve output connected to a vaporizer input.

20. (Previously Presented) The apparatus of claim 19 wherein the controller means is connected to switch the second valve means between the first valve input and the second valve input.

21. (Previously Presented) The apparatus of claim 20, wherein the controller means is connected to correspondingly switch the valve means and the second valve means.